

Inventor: Gurtej S. Sandhu et al.

Title: Methods of Forming Capacitor Constructions

Assignee: Micron Technology, Inc.

Attorney Docket No. MI22-2521

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

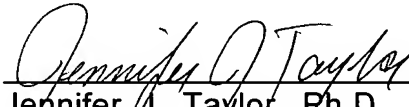
The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 10/222,330, filed August 15, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated:

March 8, 2004


Jennifer J. Taylor, Ph.D.
Reg. No. 48,711

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2521	SERIAL NO. (PRIORITY) 10/222.330
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Gurtej S. Sandhu et al.	
				FILING DATE (PRIORITY) August 15, 2002	GROUP (PRIORITY) 2813

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,783,716	Baum et al.				
	AB	6,376,327 B2	Sandhu et al.				
	AC	5,510,158	Hiramoto et al.				
	AD	6,103,567	Shih et al.				
	AE	6,432,793 B1	Reinberg				
	AF	6,395,650 B1	Callegari et al.				
	AG	5,468,687	Carl et al.				
	AH	5,508,221	Kamiyama				
	AI	6,150,209	Sun et al.				
	AJ	6,297,086 B1	Hedge et al.				
	AK	6,461,982	DeBoer et al.				
	AL	4,839,196	Itoh				
	AM	5,547,706	Thaler				

FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AN	JP06115912 A	04-1995	JP (abstract only)			x
	AO	JP02001185548 A	07-2001	JP (abstract only)			x
	AP	JP01262680 A	12-1986	JP			x
	AQ	JP05186875A	07-1993	JP			

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
AR		Crancun et al., "Low Temperature Growth of Barium Strontium Titanate Films by Ultraviolet-Assisted Pulsed Laser Deposition". Mat. Res. Symp. Vol. 617, pgs. J3.21.1-J3.21.6, 2000. Year is sufficiently early such that the month is not an issue.	
AS			

EXAMINER	DATE CONSIDERED
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.